



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Takamitsu HIGUCHI et al.

Attn: OFFICE OF PUBLICATIONS

Application No.: 10/644,989

Notice of Allowance
Mailed: 01/11/2005

Filed: August 21, 2003

Batch No.: 6923

Group Art Unit: 2818

For: SUBSTRATE FOR ELECTRONIC DEVICES, MANUFACTURING METHOD THEREOF,
AND ELECTRONIC DEVICE

Examiner: D. Vu

Docket No.: 116916

**REQUEST FOR ACKNOWLEDGMENT OF
CONSIDERATION OF DISCLOSED INFORMATION**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

An Information Disclosure Statement with Form PTO-1449 was filed in the above-captioned patent application on February 11, 2005. Applicants have not yet received back from the Examiner a copy of the Form PTO-1449 initialed to acknowledge the fact that the Examiner has considered the cited disclosed information.

The Examiner is requested to initial and return to the undersigned a copy of the subject Form PTO-1449. For the convenience of the Examiner, a copy of that form is attached.

Should there be any questions concerning this communication, please telephone the undersigned at the number set forth below.

Respectfully submitted,

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Date: March 31, 2005

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Sheet 1 of 1

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 116916	APPLICATION NO. 10/644,989	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANT(S) Takamitsu HIGUCHI et al.		
		FILING DATE August 21, 2003		GROUP 2818		
U.S. PATENT DOCUMENTS						
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
FOREIGN PATENT DOCUMENTS						
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)						
	A	Pignolet A., et al., "Large Area Pulsed Laser Deposition of Aurivillus-type Layered Perovskite Thin Films", Ferroelectrics, Overseas Publishers Associations, Amsterdam, NL, , Vol. 202, No. 1-4, 1997, pp. 285-298.				
	B	Mechin L. et al., "A combined x-ray specular reflectivity and spectroscopic ellipsometry study of CeO ₂ /yttria-stabilized-zirconia bilayers on Si(100) substrates", Journal of Applied Physics, American Institute of Physics, New York, US, Vol. 84, No. 9, 1 November 1998, pp. 4935-4940.				
	C	Matthee T., et al., "Orientation relationships of epitaxial oxide buffer layers on silicon (100) for high-temperature superconducting Yba ₂ Cu _{307-x} films", Applied Physics Letters USA, Vol. 61, No. 10, 7 September 1992, pp. 1240-1242.				
EXAMINER					DATE CONSIDERED	
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						